

## ON-CHIP p-MOSFET DOSIMETRY

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### ABSTRACT

On-chip p-FETs were developed to monitor the radiation dose of n-well CMOS ICs by monitoring the threshold voltage shifts due to radiation induced oxide and interface charge. The design employs closed geometry FETs and a zero-biased n-well to eliminate leakage currents. The FETs are operated using a constant current to greatly reduce the FET's temperature sensitivity. The dose sensitivity of these p-FETs is about  $-2.54 \text{ mV/krad(Si)}$  and the off-chip instrumentation resolves about  $400 \text{ rads/bit}$ . When operated with a current at the temperature-independent point, the output voltage,  $V_O$ , is located near  $1.5 \text{ V}$  and depends on  $V_T$ ,  $V_{T_0}$ , and  $n$ .  $V_{TT}$  is typically  $2 \text{ mV/}^\circ\text{C}$  but, with temperature compensation,  $V_{OT}$  is less than  $30 \text{ } \mu\text{V/}^\circ\text{C}$  over a  $70^\circ\text{C}$  temperature span.

### INTRODUCTION:

The use of FETs (Field-Effect Transistors) as dosimeters was pioneered by Holmes-Siedle [1]. A number of these devices have flown on earth bound satellites [2 - 4].

In recent years p-FETs dosimeters have been developed with specially grown gate oxides which have a large number of oxide traps and sensitivities of  $<1 \text{ mV/rad(Si)}$  [5] have been achieved. The sensitivity to radiation can also be enhanced by applying a large negative bias during radiation which forces more of the oxide charge to the interface. The need to operate the p-FETs with a current at the temperature-independent point has been recognized [6, 7].

In the following effort, a p-FET dosimeter is developed under the constraint that the dosimeter be useful in predicting the radiation dose of an IC fabricated with a non-radiation hardened CMOS process. As shown in Fig. 1, two p-FETs are included on the RADMON, Radiation Monitor, which also includes an SEU-SRAM for monitoring particle upsets. The RADMON was designed for use on the STRV (Space Technology Research Vehicle) to be launched in 1994.

The p-FET uses available CMOS biases during measurement and is unbiased when not being measured. This approach to biasing is intended to provide a known bias environment. In certain applications, the availability of spacecraft power is unpredictable. Thus being unpowered, during dosing, provides a known bias environment.

On-chip dosimetry provides the advantage that the dose is measured directly. This reduces the uncertainty inherent in dosimetry calculations which are complicated especially for highly embedded electronics.

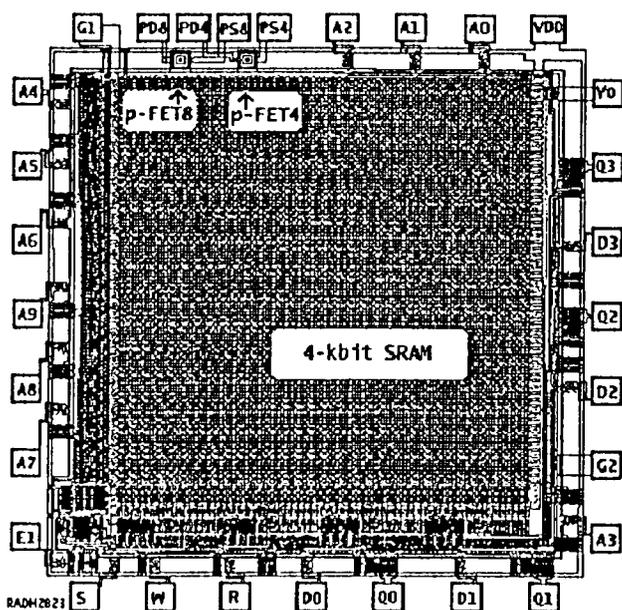


Figure 1. STRV-RADMON Chip 1.6 mm x 1.7 mm.

### P-FET DESIGN

The layout of the p-FET, shown in Fig. 2, and features a closed geometry design where the drain is completely surrounded by the source. The cross section of the device, shown in Fig. 3, indicates that the n-well and source are separated so that they can operate at slightly different biases. In addition the n-well is grounded. In a CMOS circuit the n-

well is normally connected to VDD. These design precautions minimize leakage currents.

### COMPLETE p-FET MODEL EQUATIONS

As seen in Fig. 3, the gate is connected to the drain. This ensures that the p-FET is operated in the saturation region. In saturation the drain current is given by [7]:

$$(1) I_D = \frac{B}{2} \frac{(V_{O_0} - V_T)^2}{1 + \theta(V_O - V_T)}$$

where  $V_O$  is the p-FET output voltage,  $B = KP \cdot W/L$ ,  $KP = \mu_0 \cdot C$  and  $V_T$  is the absolute value of the p-FET threshold voltage. The other parameters are  $W$  and  $L$  are the effective channel width and length respectively.  $\mu_0$  is the zero-field channel mobility,  $C$  is the gate oxide capacitance per unit area, and  $\theta$  is the mobility electric-field degradation parameter.

This equation is plotted in Fig. 4 which shows that the "temperature independent" point is in fact ill-defined when viewed in detail.

The above parabolic equation was linearized by taking the square root and then applying the Taylor Series expansion to the  $\theta$  term:

$$(2) \sqrt{I_D} = \sqrt{B/2} (V_O - V_T) \left[ 1 - \frac{\theta}{2} (V_O - V_T) \right]$$

The temperature and dose dependence of  $V_T$ ,  $B$ , and  $\theta$  are given below. For the threshold voltage:

$$(3) V_T = V_{T_0} + V_{T_T}(T - T_0) + V_{T_D} \cdot D$$

where  $T_0$  is the reference temperature taken as 300 K,  $V_{T_T} = \partial V_T / \partial T |_{T \rightarrow T_0}$  and  $V_{T_D} = \partial V_T / \partial D |_{D \rightarrow 0}$ . The temperature and dose dependence of  $B$  is given by:

$$(4) B = B_0 (T/T_0)^{-n} + B_D \cdot D$$

where  $B_D = \partial B / \partial D |_{D \rightarrow 0}$  characterizes the mobility temperature dependence, and  $T$  is the absolute temperature. Note that:

$$(5) B_T = \partial B / \partial T = -n \cdot B / T$$

The temperature and dose dependence of  $\theta$  is given by:

$$(6) \theta = \theta_0 + \theta_T \cdot (T - T_0) + \theta_D \cdot D$$

where  $\theta_T = \partial \theta / \partial T |_{T \rightarrow T_0}$  and  $\theta_D = \partial \theta / \partial D |_{D \rightarrow 0}$ .

The p-FET output voltage follows from Eq. 2

after solving the quadratic equation in  $V_O$ :

$$(7) V_O = V_T + \frac{1}{\theta} \cdot (1 - \sqrt{1 - \theta \cdot \sqrt{B \cdot I_D / B_m}})$$

where the sign of the square root sign is negative which can be seen in the limit where  $\theta = 0$ . Next  $I_{D_m}$  is found from the above equation by setting  $\partial V_O / \partial T = 0$  and solving the resulting quadratic equation for  $I_{D_m}$ :

$$(8) \sqrt{I_{D_m}} = -\frac{A}{2} - C \pm D \cdot \sqrt{1 + B \cdot (C + A/4)}$$

The sign of the square root is positive for  $\theta > 0$  and negative for  $\theta < 0$ . The primary parameters are:

- (9)  $A = a2b/d2$
- (10)  $B = b$
- (11)  $C = c/d$
- (12)  $D = a/d$

and the secondary parameters are:

- (13)  $a = V_{T_T} - V_{T_0} / \theta_m^2$
- (14)  $b = \theta_m \cdot \sqrt{B/B_m}$
- (15)  $c = -\theta_T / \theta_m^2$
- (16)  $d = [(2\theta_T / \theta_m) - (n/T_m)] / \sqrt{2B_m}$

Once  $I_{D_m}$  is calculated using the above algorithm,  $V_{D_m}$  is calculated using Eq. 25 evaluated at  $T_m$ :

$$(17) V_{D_m} = V_{T_m} + \frac{1}{\theta_m} \cdot (1 - \sqrt{1 - \theta_m \cdot \sqrt{B \cdot I_{D_m} / B_m}})$$

### SIMPLIFIED p-FET MODEL EQUATIONS ( $\theta = 0$ )

Physical insight results by deriving the model equations for  $\theta = 0$ . From Eq. 2 the output voltage is:

$$(18) V_O = V_T + \sqrt{2I_D/B}$$

The temperature sensitivity of  $V_O$  is calculated using Eqs. 3 and 4 for  $D = 0$ . The result is plotted in Fig. 5. If the current is chosen correctly, the operating temperature span is more than 70°C for less than 1mV change in  $V_O$ . This translates in to a temperature sensitivity for  $V_O$  of less than 30  $\mu V/^\circ C$ . If the uncertainty in the current is  $\pm 1$  percent, the operating span is reduced to 60°C for less than a 1mV change in  $V_O$ . In general the current must be chosen within 1 percent of the target current.

The current at the temperature independent point for  $\theta = 0$  follows by setting the temperature differential of Eq. 18 to zero:

$$(19) I_{D_m} = 2B_m^3 (V_{T_T} / B_{T_m})^2$$

Substituting  $B_m = KP_m W/L$  and Eq. 5 leads to:

$$(20) I_{D_m} = 2KP_m(VT_T \cdot T_m/n)^2 W/L$$

This shows that  $I_{D_m}$  depends on the FET geometry and the silicon parameters. Thus once the silicon parameters are known,  $I_{D_m}$  is known given  $T_m$  and  $W/L$ .

The output voltage at the temperature independent point is found by substituting Eqs. 5 and 19 into Eq. 18:

$$(21) V_{O_m} = VT_m - 2VT_T \cdot T_m/n$$

which shows that  $V_{O_m}$  is independent of the FET  $W/L$  geometry and depends only on the silicon parameters. Values for  $V_{O_m}$  range between 1.5 and 2 V for modern p-FET devices.

It is of technological interest to note that  $V_{O_m}$  is independent of temperature for  $n = 2$ . This means that a true temperature independent point can be achieved. Combining Eqs. 4, 5, 18, and 19 leads to:

$$(22) V_{OT} = \partial V_{O_m} / \partial T = VT_T [1 - (T/n) \cdot 1-n/2]$$

This shows that  $V_{OT} = 0$  at  $T = T_m$  for any  $n$  and  $V_{OT} = 0$  for  $n = 2$  for all  $T$ .

#### p-FET TEMPERATURE DATA ANALYSIS

The p-FETs were measured in packages using an hp4062 parametric test system with an oven. The measurements were obtained by forcing  $V_0 = 3$  V and measuring  $I_{D_5}$ . Then four additional currents were forced at  $\sqrt{I_{D_1}} = 0.2 \cdot \sqrt{I_{D_5}}$ ,  $\sqrt{I_{D_2}} = 0.401/15$ ,  $\sqrt{I_{D_3}} = 0.6 \cdot \sqrt{I_{D_5}}$ , and  $\sqrt{I_{D_4}} = 0.8 \cdot \sqrt{I_{D_5}}$ . These IV points were fitted using Eq. 23. The  $B$ ,  $VT$ , and  $\theta$  values are listed in Table 1 for three temperatures estimated to be accurate within 1°C.

The experimental data, shown in Fig. 6, was fitted using the method of least squares. In the analysis the following parabolic equation was fitted to the data and then the coefficients were related to the parameters in Eq. 2.

$$(23) \sqrt{I_D} = a_0 + a_1 \cdot V_0 + a_2 \cdot V_0^2$$

where

$$(24) a_0 = -\sqrt{(B/2)} \cdot VT \cdot (1 + \theta \cdot VT/2)$$

$$(25) a_1 = \sqrt{(B/2)} \cdot (1 + \theta \cdot VT)$$

$$(26) a_2 = -\sqrt{(B/2)} \cdot \theta/2.$$

The parameters  $a_0$ ,  $a_1$ , and  $a_2$  are used to obtain the FET parameters for each of the IV curves. The solution for  $VT$  was obtained by recognizing that  $V_0 = VT$  at  $I_D = 0$ . This leads to a quadratic equation whose solution

is:

$$(27) VT = a_1 / (2a_2) \cdot (-1 + \sqrt{1 - 4a_0 a_2 / a_1^2})$$

The sign of the square root is positive for positive  $VT$  values. Next the solution for  $B$  was found by recognizing that at  $V_0 = VT$ ,  $\partial \sqrt{I_D} / \partial V_0 |_{V_0=VT} = \sqrt{(B/2)} = 2a_2 \cdot VT + a_1$ ; thus

$$(28) B = 2(2a_2 \cdot VT + a_1)^2$$

Finally,  $\theta$  follows by recognizing that the parameter  $a_2 = -(\theta/2) \cdot \sqrt{(B/2)}$ ; thus

$$(29) \theta = -1/[VT + a_1/(2a_2)]$$

The temperature parameters for  $VT$  and  $\theta$  were extracted by least squares fitting the data using Eqs. 3 and 6. The temperature parameter for  $B$  was extracted from Eq. 4 after it was linearized by taking the logarithm. The temperature parameters are listed in Table 2.

#### p-FET DOSE DATA ANALYSIS

The p-FET dose dependence was determined using Cobalt-60 irradiation. The devices were irradiated with their lids on, at room temperature, at 40 rads/sec, and at zero bias. The p-FETs were measured within 15 minutes after Cobalt-60 irradiation.

The p-FET irradiation results, shown in Fig. 7, were least squares fitted using the algorithm given in Eq. 23. This produced a set of  $VT$ ,  $B$ , and  $\theta$  values for each dose value. These are plotted in Figs. 8 to 10 for four p-FETs. The radiation results are listed in Table 3.

The  $VT$  values, plotted in Fig. 8, show some nonlinearity with dose because of the high dose rate of 40 rads/sec. The  $VT$  anneals after one-week, as shown at the highest dose value. Using this value, the slope of the  $VT$  vs dose curve is  $VTD = -1.56$  mV/krad(Si). These results are explained by the build-up of positive oxide and interface charge and loss of oxide charge during anneal.

The  $B$  values, shown in Fig. 9, are separated by the difference in the  $W/L$  ratios between the p-FETs. The  $B$  continues to shift after an 18 hr anneal shown at 120 in Fig. 10. These results are explained by the build-up of positively charged interface states during irradiation and anneal and this affects the zero-field hole channel mobility.

The  $\theta$  values are shown in Fig. 10. These curves are clustered about the  $W/L$  ratio and

they continue to shift after an 18 hr anneal shown at 120 in Fig. 10. Notice that  $\theta$  is positive initially and negative after irradiation and anneal.

As far as the author's know, the field-dependent mobility after dosing was discussed only once before in the literature [8]. The positive and negative  $\theta$  values are explained by the mobility values shown in Fig. 11. These values were calculated from:

$$(30) \mu = 2L \cdot ID / [W \cdot C_o \cdot (V_o - V_T)^2]$$

where  $C_o$  was calculated for a 21.8 nm oxide. As seen in Fig 11, for  $D = 0$ , the mobility decreases as the field increases. After radiation, the mobility is degraded at zero-field and this explains the decrease in  $\beta$  with dose. But after a heavy dose the mobility increases with field. This is explained by the channel charge shielding the interface states and preventing the interface states from acting as scattering centers.

### 5.10 DOSIMETRY

The damage factor for the dose calculations is derived in this section. Since the dose is measured at the constant current,  $ID_m$ , the radiation dose sensitivity of  $V_o$  is greater than  $V_{TD}$ . This is evident in Fig. 8 where the spread in the curves is wider at  $ID = ID_m$  than at  $ID = 0$  due to  $\beta$ 's dose dependence.

In this section the damage factor,  $V_{OD}$ , for  $\theta = 0$  is calculated by differentiating Eq. 5.10 with respect to dose. Then the constant current  $ID_m$  given in Eq. 19 is substituted in to the result. The damage factor is:

$$(31) V_{ODm} = \partial V / \partial D = V_{TD} - V_{TT} \cdot \beta_{Dm} / \beta_{Tm}$$

Results for a p-FET were calculated using  $V_{TD} = -1.86$  mV/krad(Si),  $KP_{Dm} = -0.053$  ( $\mu A/V^2$ )/krad (Si),  $V_{TT} = +1.80$  mV/ $^{\circ}C$ , and  $KP_{Tm} = -0.14$  ( $\mu A/V^2$ )/ $^{\circ}C$ . This leads to a damage factor of  $V_{ODm} = -2.54$  mV/krad(Si).

### CONCLUSION

The use of on-chip p-FET dosimeters is quite feasible and provides good sensitivity if the FETs are operated at the temperature independent point. The use of on-chip p-FETs provides a direct measure of the worst case radiation dose experienced by the associated CMOS IC.

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### ACKNOWLEDGMENT:

The research described herein was performed by the Center for Space Microelectronics Technology, Jet Propulsion Laboratory, California Institute of Technology, and was sponsored by the Strategic Defense Initiative Organization. The authors are indebted to MOSIS for brokering the CMOS fabrication. File: NSRE3620.DOC

Table 1. Flight p-FET4 parameters (W12P4C26)

T $^{\circ}C$	VT  V	$\beta$ mA/V <sup>2</sup>	$\theta$ 1/v
30	0.874	1.100	0.056
75	0.800	0.891	0.041
125	0.703	0.708	0.027

Table 2. Flight p-FET Parameters  
( $T_c = 20^\circ\text{C}$ ,  $T_m = 10^\circ\text{C}$ , W12P4C26)

PARAM	UNITS	MEAN	STDEV
w	urn	182	
L	urn	4	
$V_{T0}$	V	$-0.8944 \pm 0.0055$	
$V_{TT}$	mV/ $^\circ\text{C}$	$1.8002 \pm 0.0800$	
$\beta_0$	$\text{mA}/\text{V}^2$	$1.1667 \pm 0.0126$	
$KP_0$	$\mu\text{A}/\text{V}^2$	$25.6421 \pm 0.2774$	
n	--	$1.6139 \pm 0.0528$	
$\theta_0$	1/v	$0.0593 \pm 0.0014$	
$\theta_T$	1/(kV $\cdot^\circ\text{C}$ )	$-0.3153 \pm 0.0209$	
$V_{Tm}$	v	-0.9125	
$B_m$	$\text{mA}/\text{V}^2$	1.2339	
$\theta_m$	1/V	0.0624	
$I_{Dm}$	$\mu\text{A}$	244	
$V_{Om}$	V	-1.55	

Table 3. Ground Test p-FET Cobalt-60 Radiation Parameters W12P4C28

PAR.	UNITS	MEAN	STDEV
VTD	mV/krad(Si)	-1.85620	0.097
$\beta_D$	$\text{PA}/\text{V}^2/\text{krad}(\text{Si})$	$-2.401 \pm 0.048$	
$KP_D$	$\mu\text{A}/\text{V}^2/\text{krad}(\text{Si})$	$-0.053 \pm 0.001$	
$\theta_D$	1/kV/krad(Si)	$-0.841 \pm 0.026$	

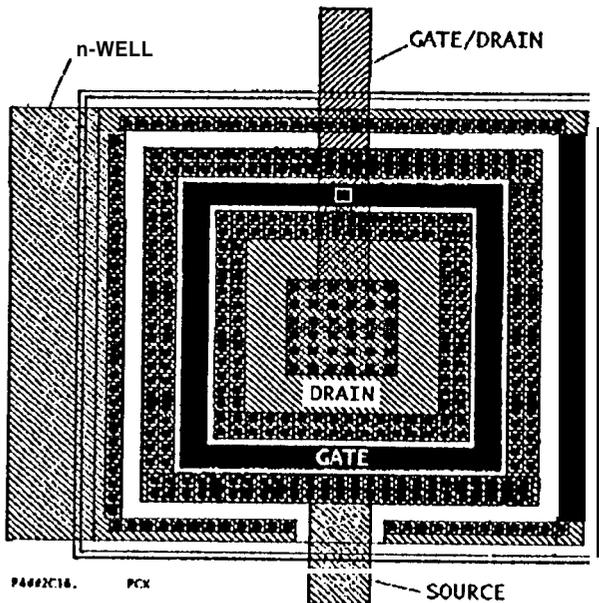


Figure 2. p-FET, MP4, layout where  $L = 4 \mu\text{m}$  and  $W = 182 \mu\text{m}$ . (File: P4##2C16.PCX)

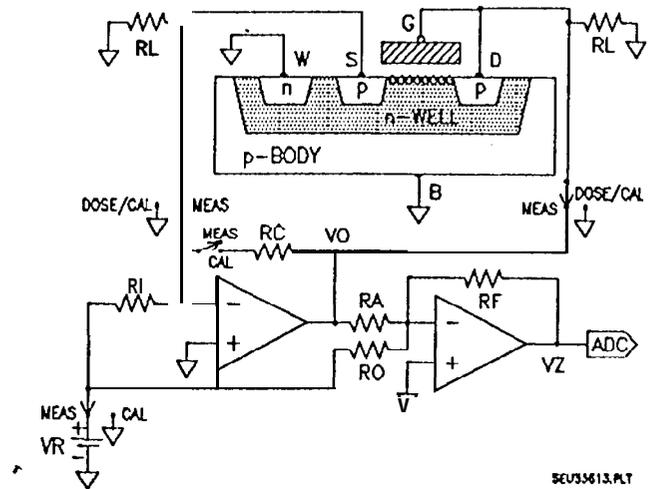


Figure 3. p-FET total dose circuitry.

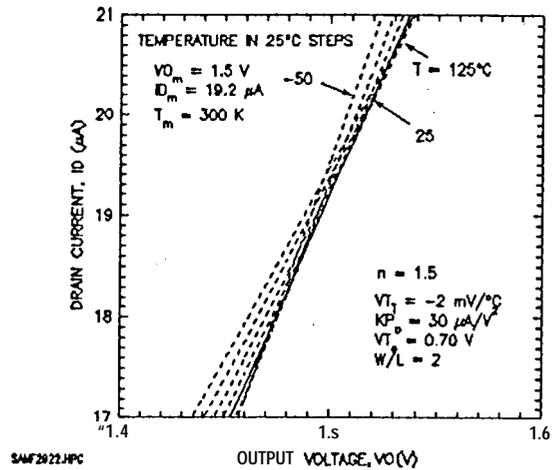


Figure 4. Expanded p-FET IV characteristics showing that the "temperature independent" point is not a point.

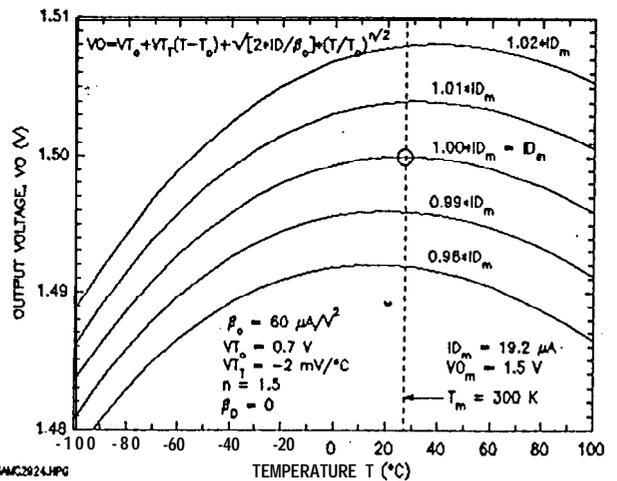


Figure 5. The temperature and current dependence of the p-FET output voltage.

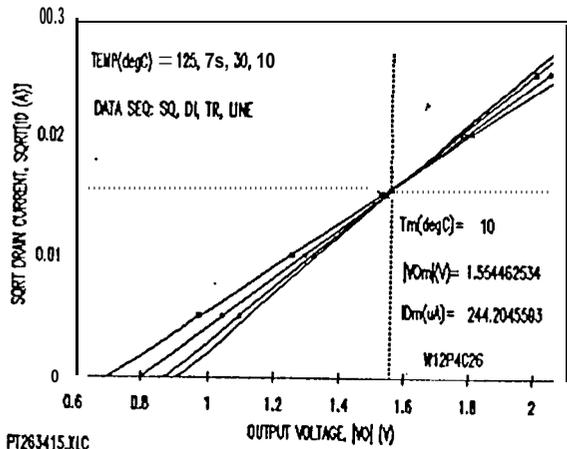


Figure 6. Temperature dependence of flight p-FET W12P4C26.

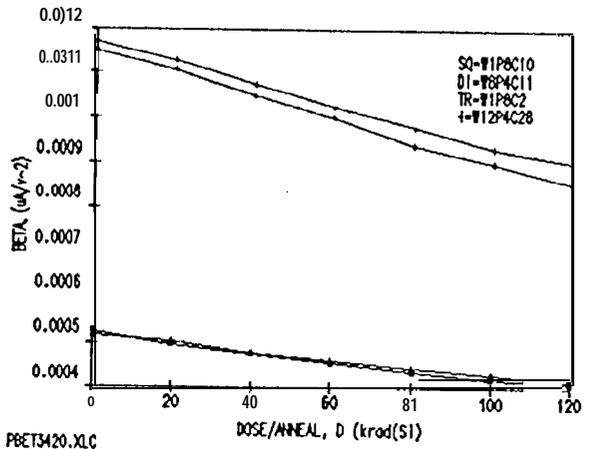


Figure 9. 1.2- $\mu\text{m}$  CMOS p-FET beta Cobalt-60 dose/anneal dependence.

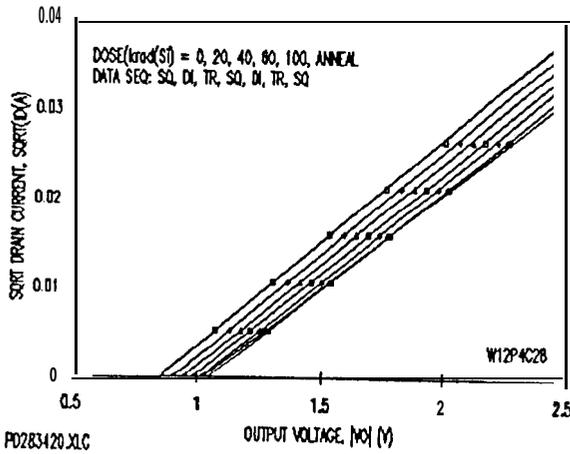


Figure 7. p-FET Cobalt-60 dose/anneal dependence where the point at 120 was measured 18 hr after last dose.

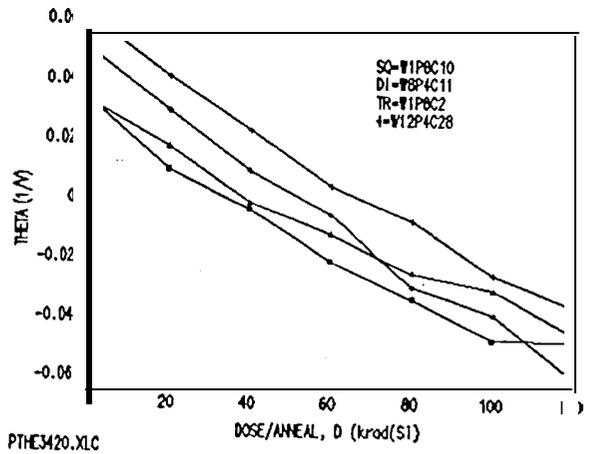


Figure 10. 1.2- $\mu\text{m}$  CMOS p-FET theta Cobalt-60 dose/anneal dependence.

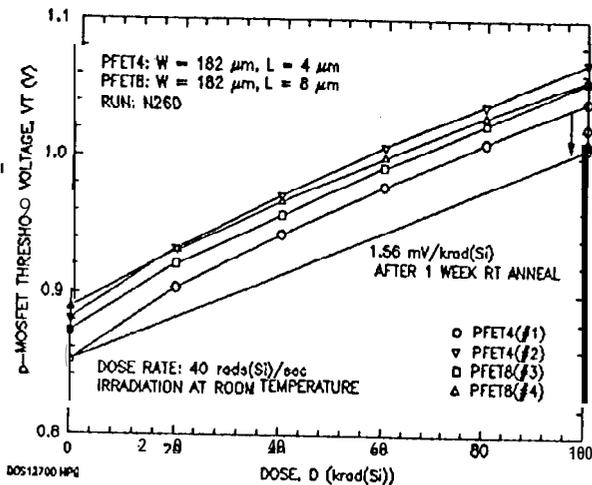


Figure 8. 1.2- $\mu\text{m}$  CMOS p-FET total dose response after one-week anneal.

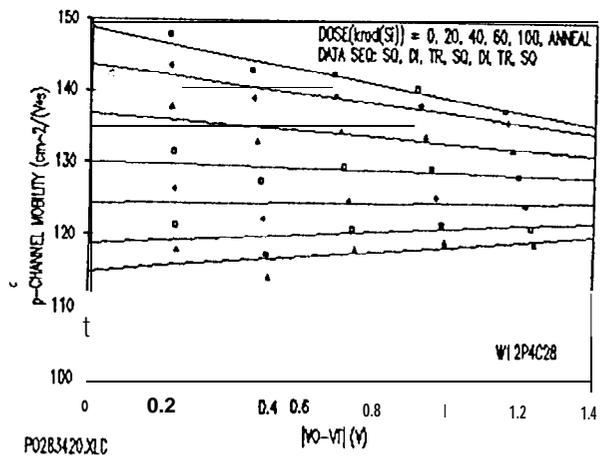


Figure 11. 1.2- $\mu\text{m}$  CMOS p-FET channel mobility after Cobalt-60 dose and anneal. Chip No. W12P4C28.